

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of:)
) Examiner:
Yuichiro Shindo)
) Group Art Unit:
Application No.:)
)
Corresponding International Filing No.:)
 PCT/JP2004/015777
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Filed: Herewith)
)
For: HIGH PURITY HAFNIUM,)
TARGET AND THIN FILM)
COMPRISING SAID HIGH)
PURITY HAFNIUM, AND)
METHOD FOR PRODUCING)
HIGH PURITY HAFNIUM)

Mail Stop PCT
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

FIRST PRELIMINARY AMENDMENT

Sir:

Before calculating the filing fee, please amend the above-identified patent application as follows.

Amendments to the Claims are reflected in the listing of claims which begins on page two of this paper.

Remarks begin on page four of this paper.